European Advanced Accelerator Concepts Workshop 5 June 2013

High sensitivity gas-density profilometry for laser- and beamdriven plasma acceleration experiments

Status report

Group for Accelerator Physics, Universität Hamburg, and Group for Linear Accelerator Research (FLA), FH Division, Deutsches Elektronen-Synchrotron DESY

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In collaboration with S. Hooker and his group

Wednesday, 5 June 13

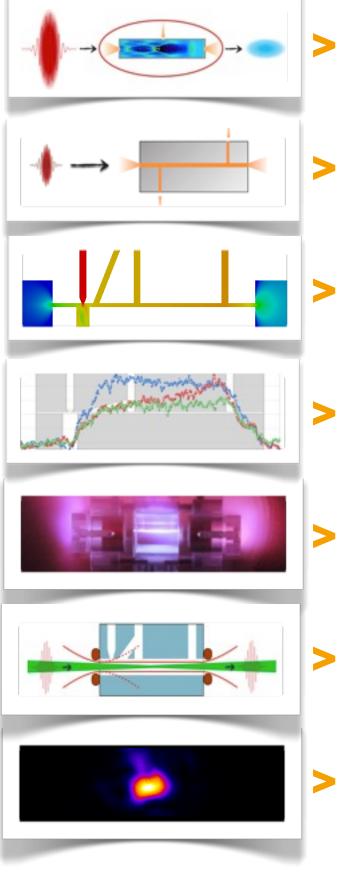
Lucas Schaper



Part of the LAOLA collaboration



Outline



- Motivation
- Controlled injection mechanisms
- Target simulation and fabrication
- Longitudinal gas density profile and absolute calibration
- Transverse density shaping and single shot guiding
- Discharge seeding
- Summary and conclusion

Plasma acceleration: Stability and reproducibility

Electron beam fluctuations may originate from

variations in laser pulse parameters

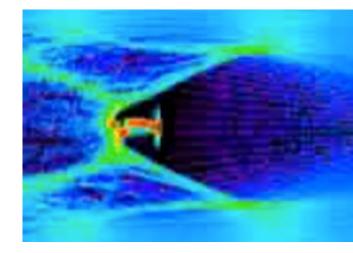
 \rightarrow spatial and temporal energy profiles, pointing

Improve control over and stabilize crucial laser parameters

e.g. Popp et al., Phys. Rev. Lett. 105, 215001 (2010) Gonsalves et al., Phys. Plasmas 17, 056706 (2010)

amplified through nonlinear processes

 \rightarrow e.g. wavebreaking, ...



energy spread

Control of phase-space population by controlled injection

variations in target conditions

 \rightarrow spatial and temporal 3D density profile

Develop stable, tailored plasma sources

e.g. Osterhoff et al., Phys. Rev. Lett. 101, 085002 (2008)

dephasing

longitudinal profile taper

> Density down ramp injection

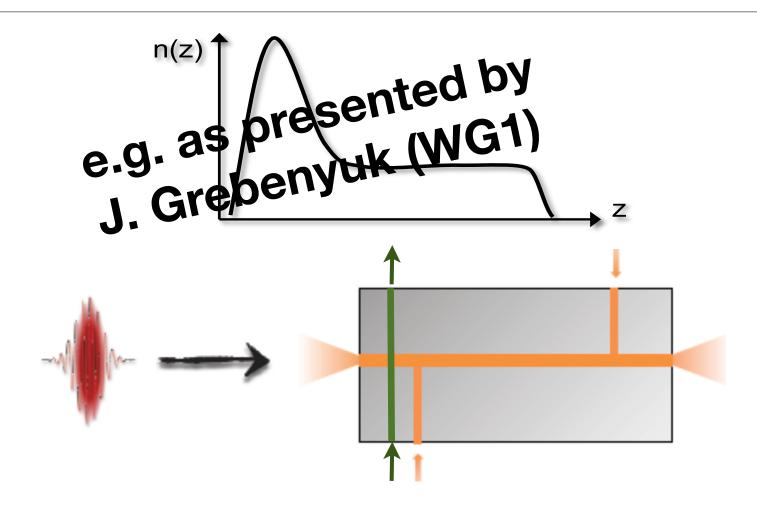


> Density down ramp injection

n(z) e.g. as presented by J. Grebenyuk (WG1) Ζ

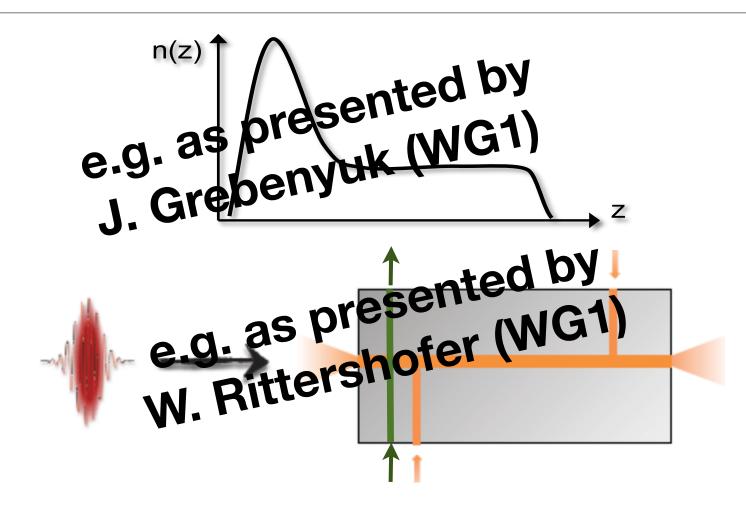
> Density down ramp injection

> Ionisation injection



> Density down ramp injection

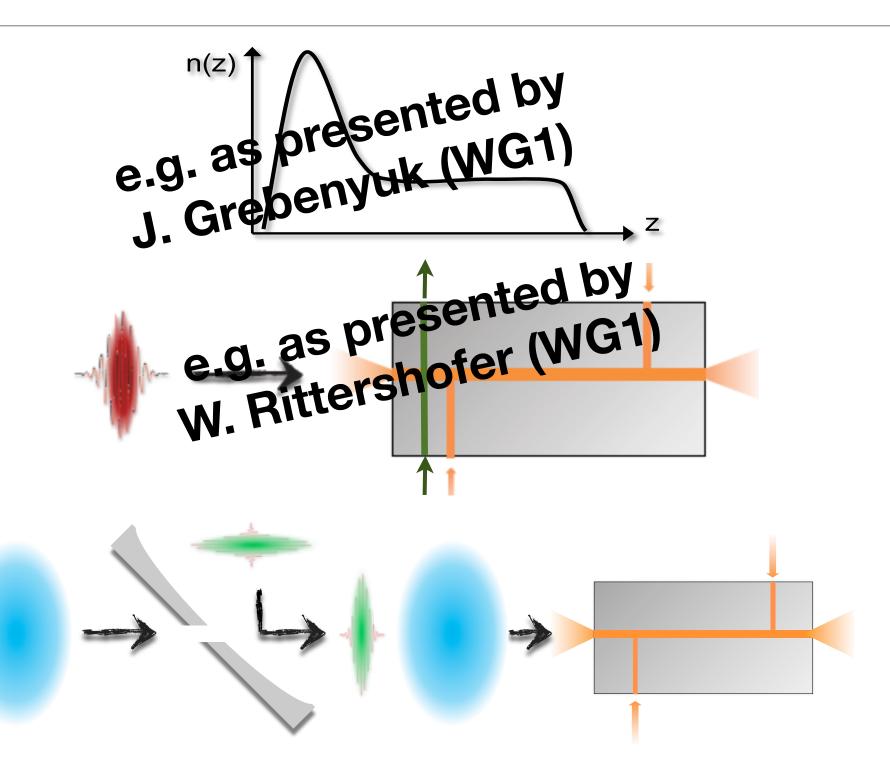
> Ionisation injection



> Density down ramp injection

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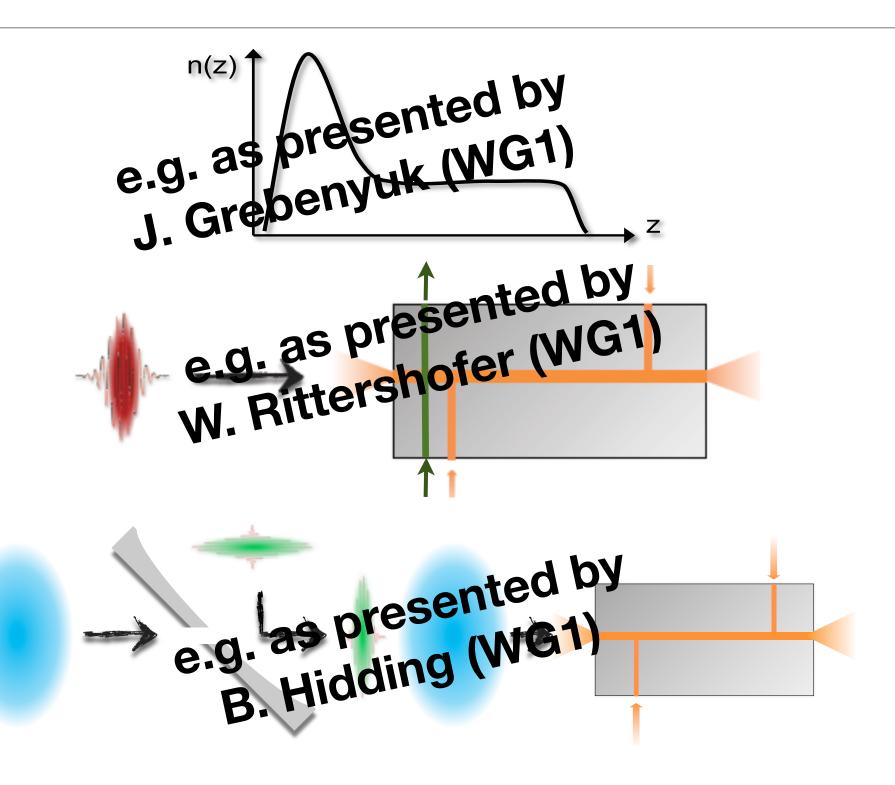
> mediated ionisation injection



> Density down ramp injection

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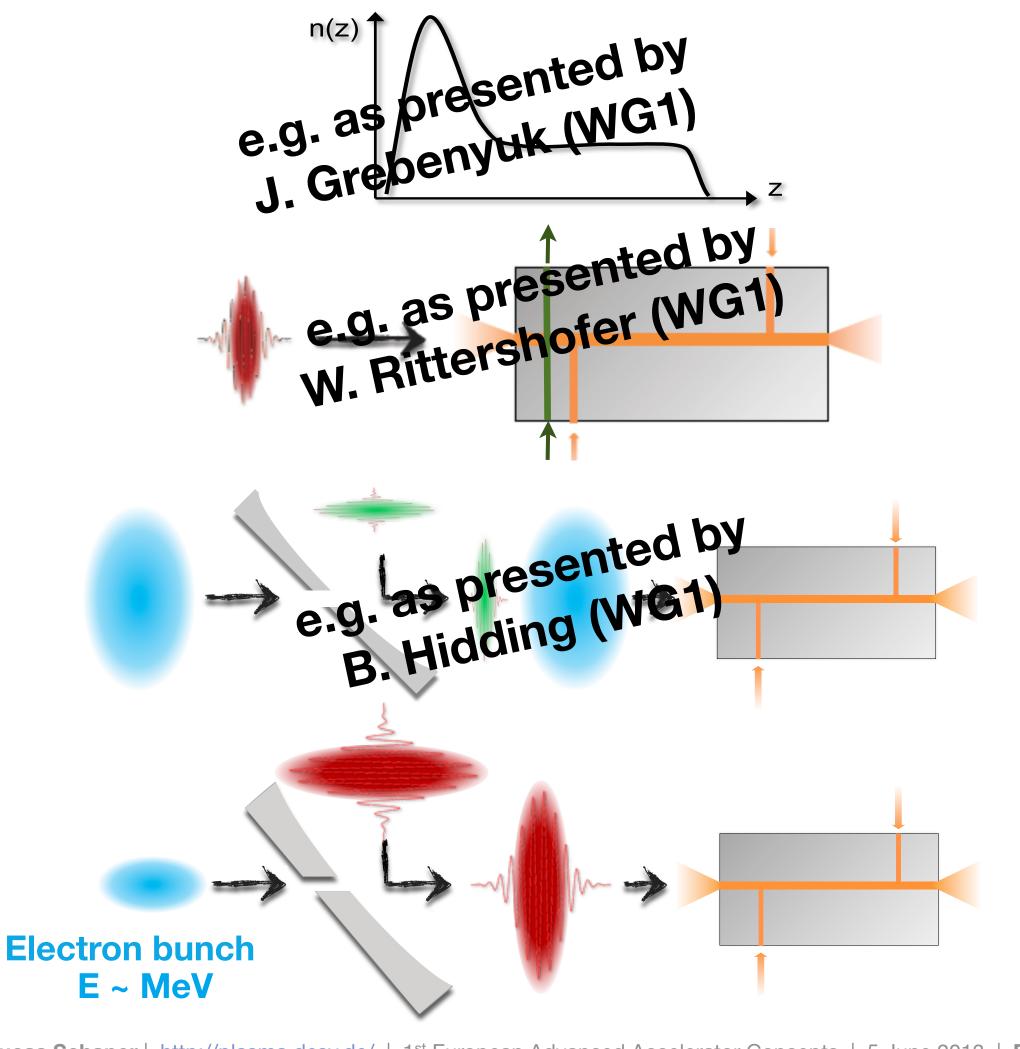
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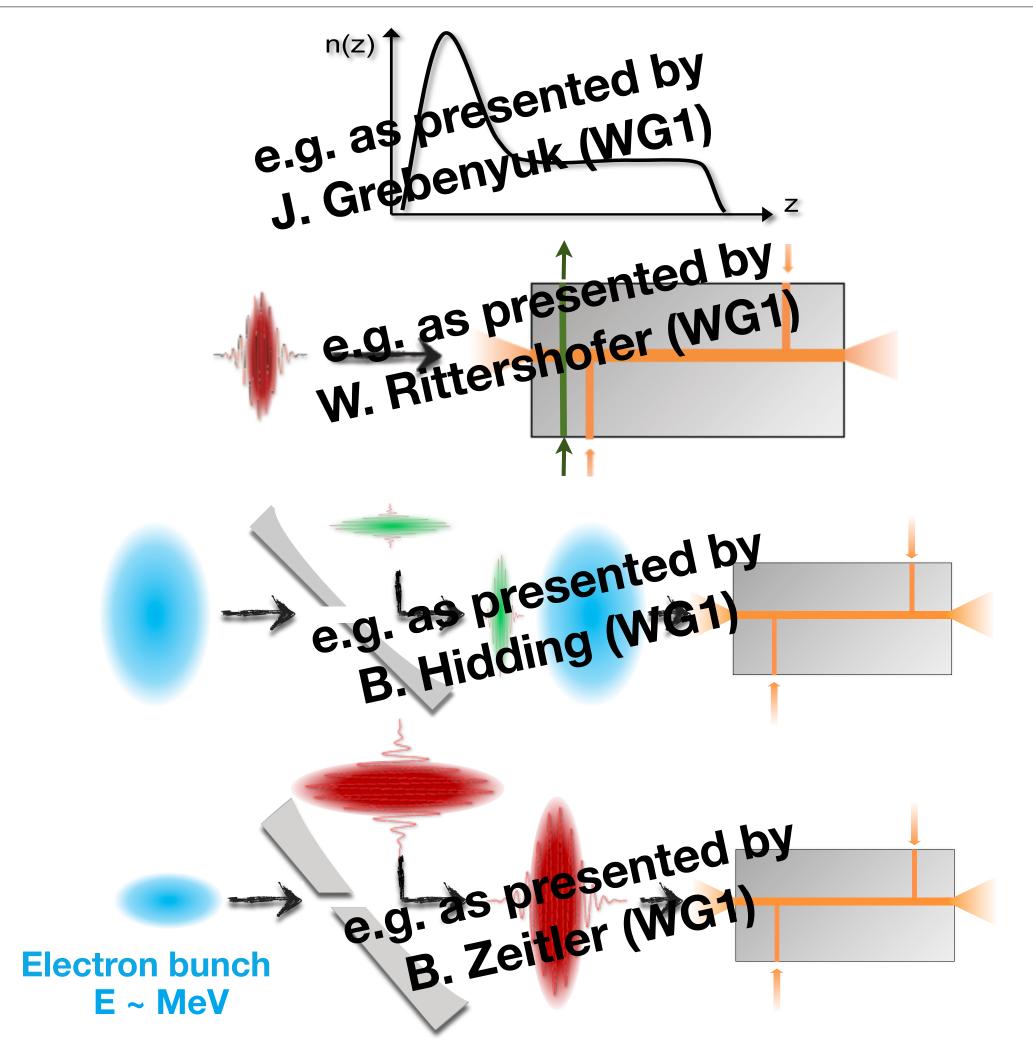
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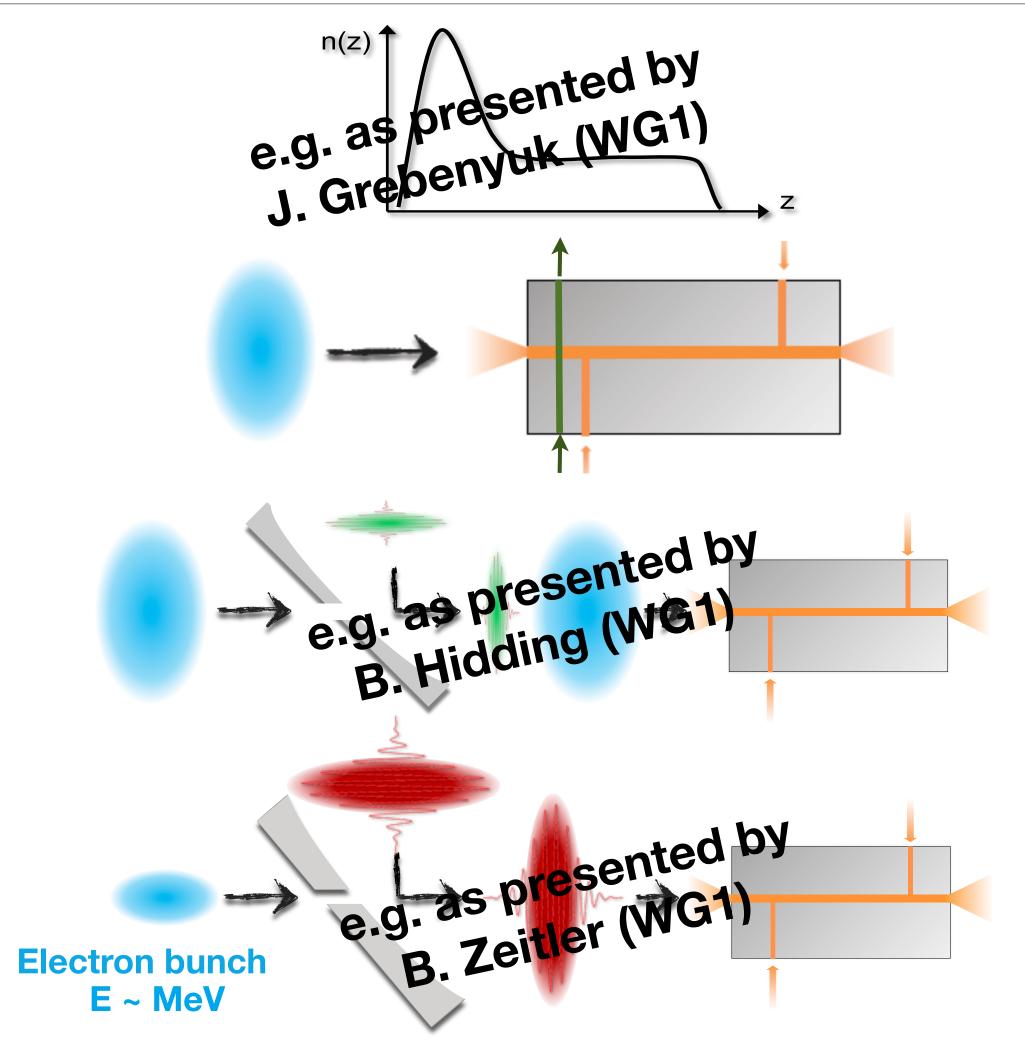
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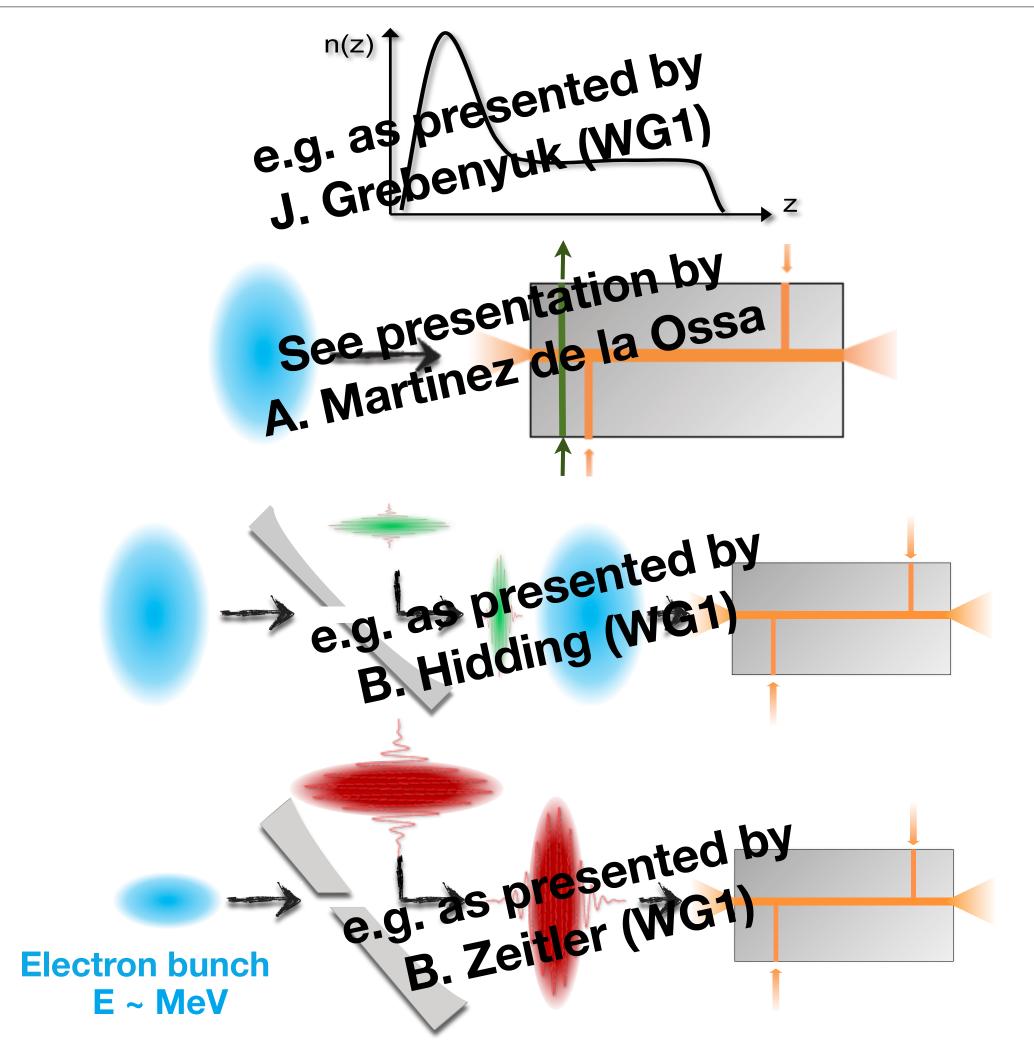
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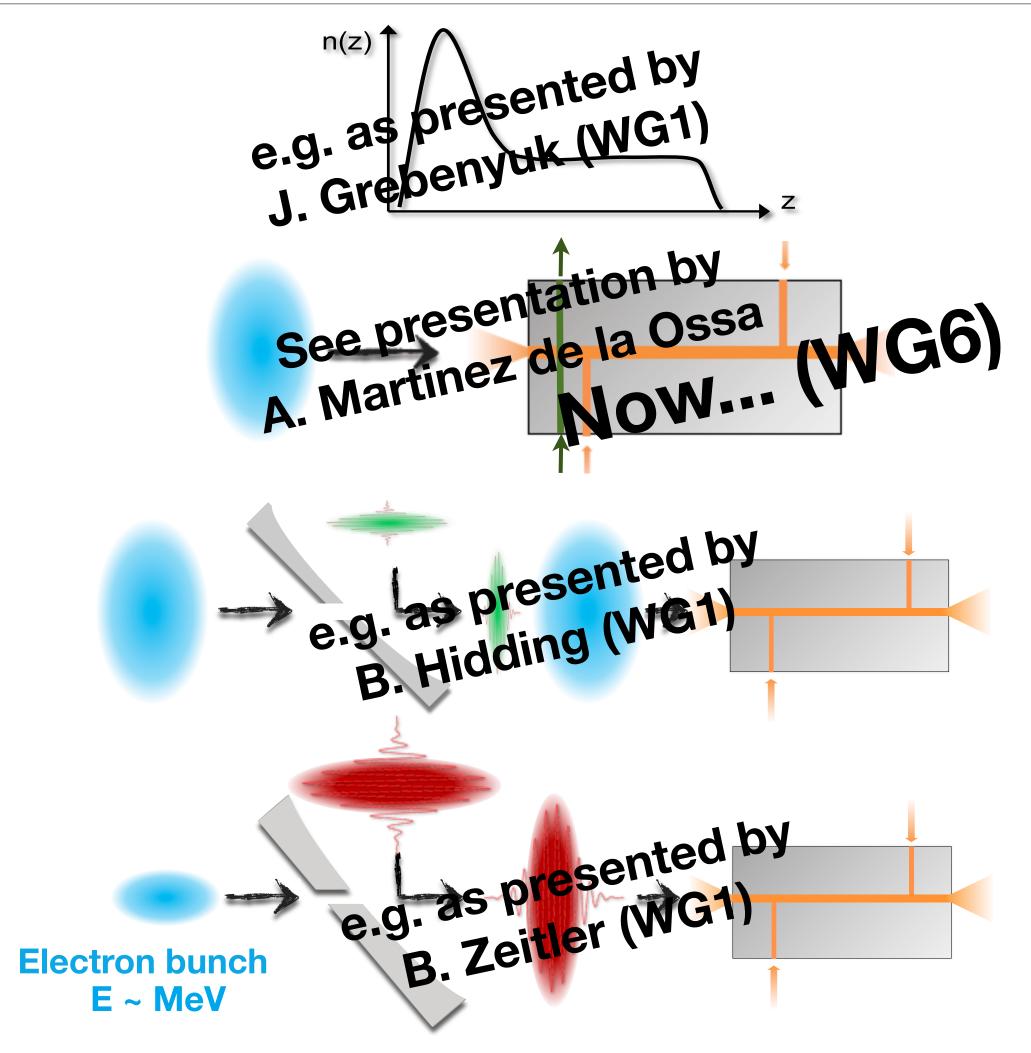
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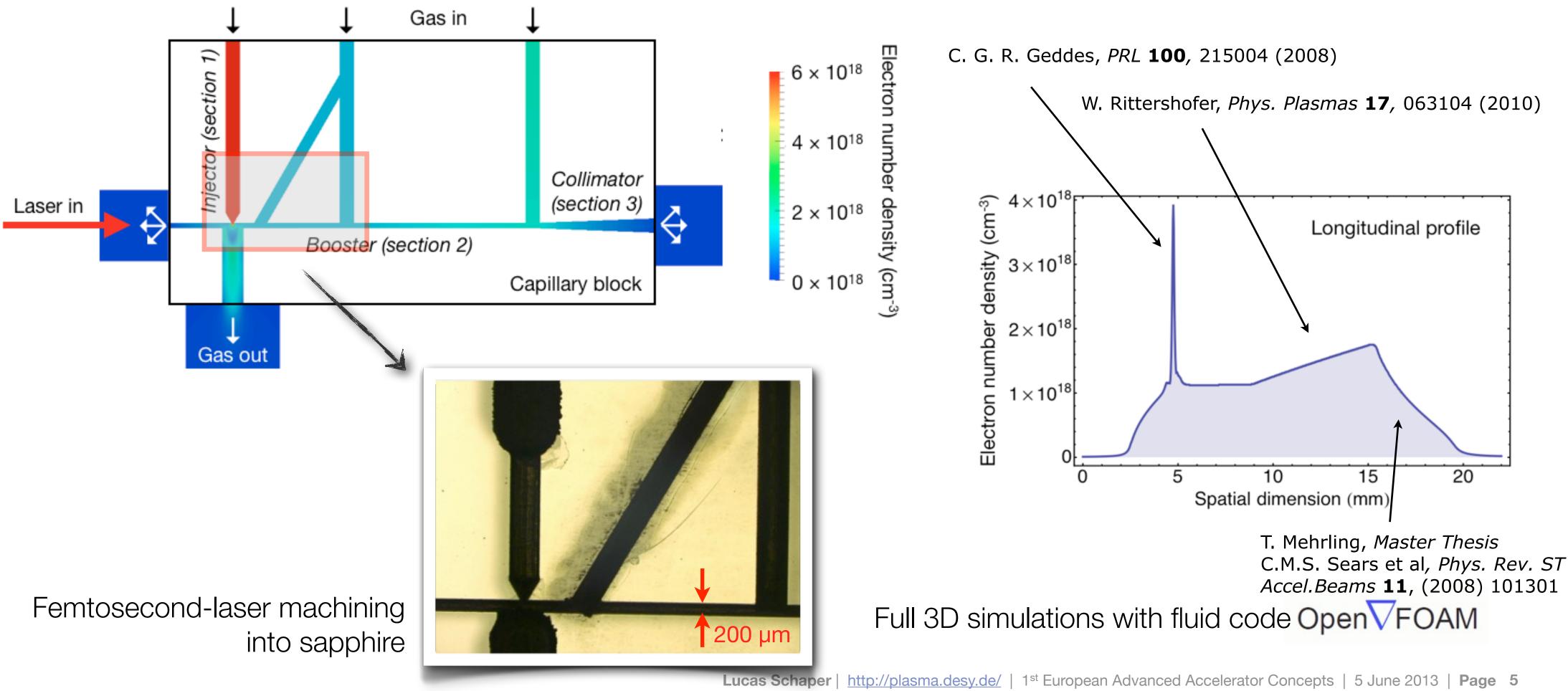
Ionisation injection

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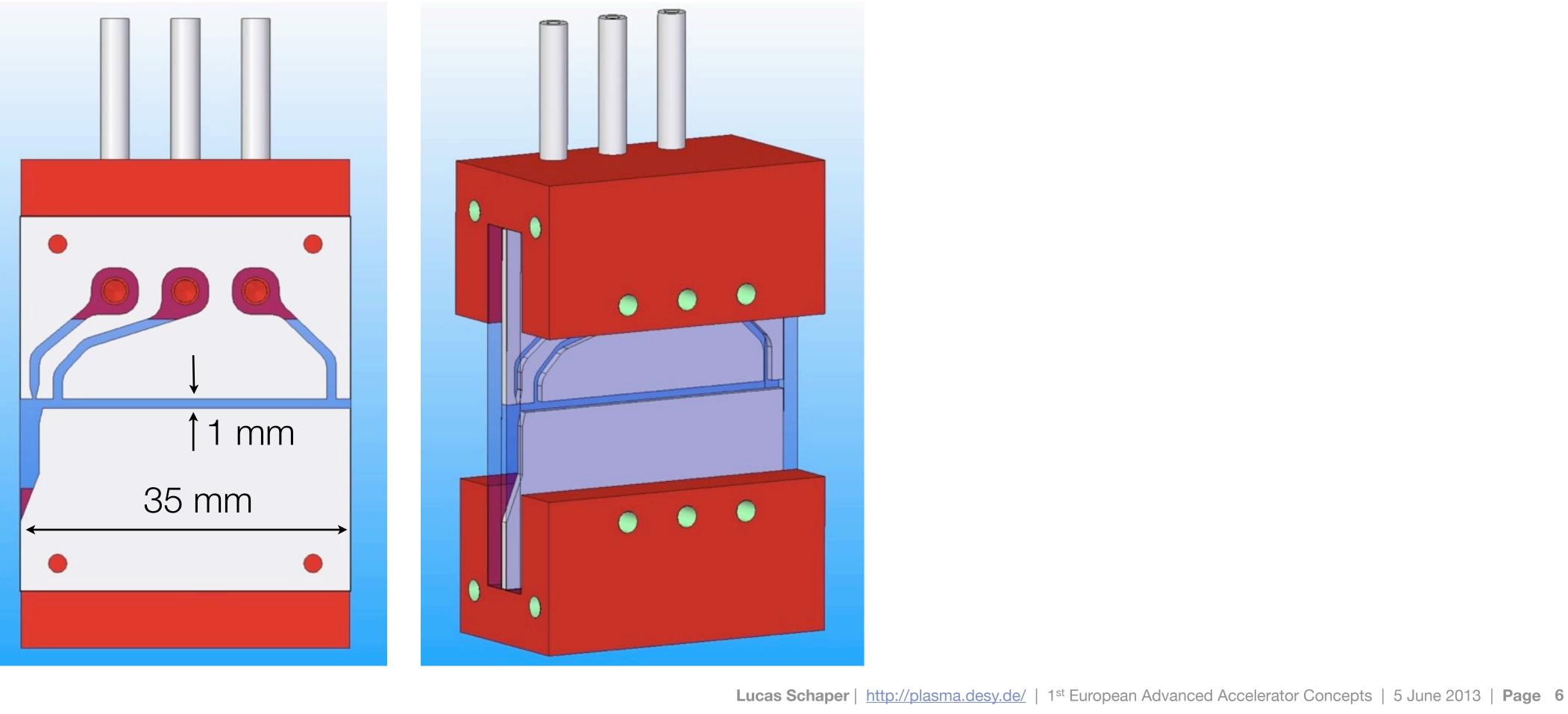
The goal: development of tailored plasma sources for controlled electron injection, acceleration and emission

Example: Segmented capillary discharge waveguide (injector, booster, collimator)



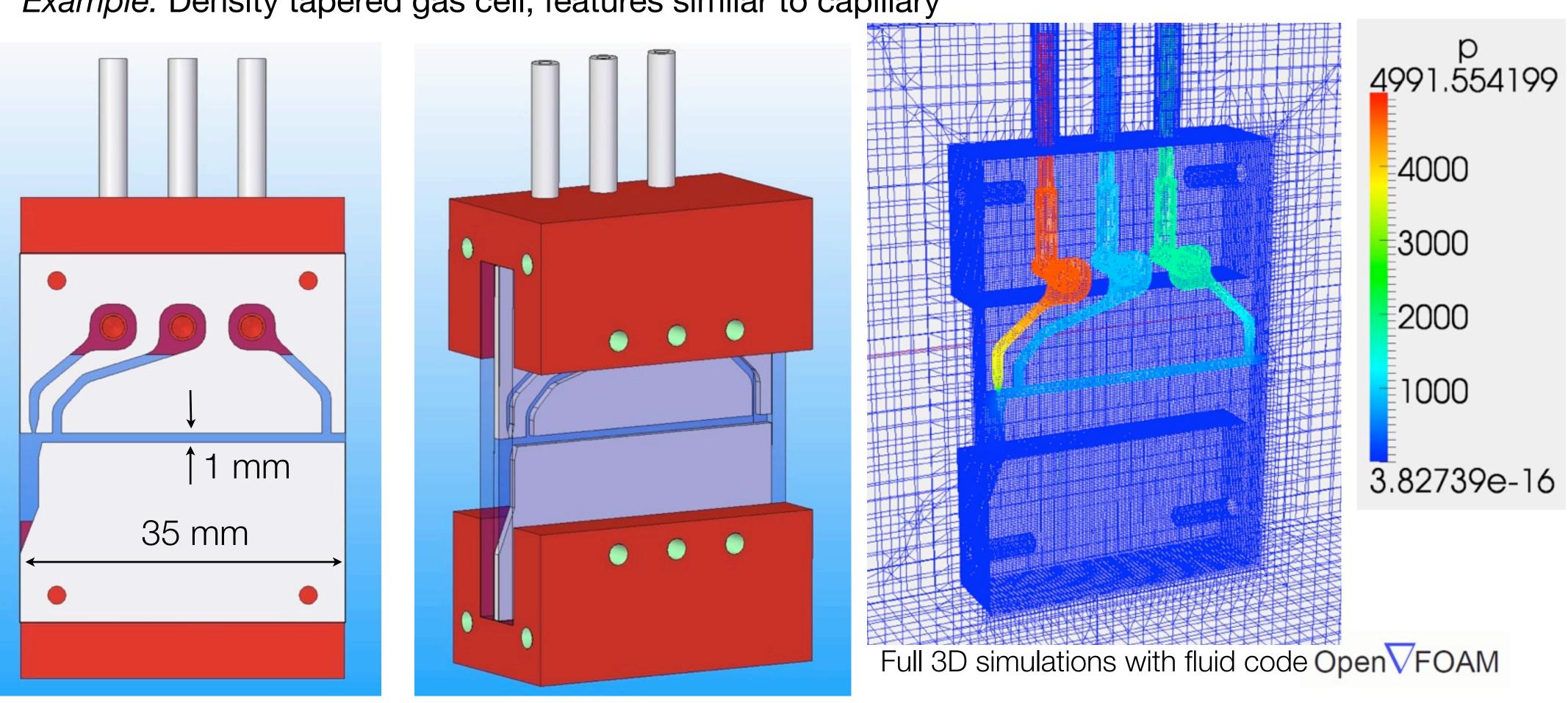
The goal: development of tailored plasma sources for controlled electron injection, acceleration and emission II

Example: Density tapered gas cell, features similar to capillary

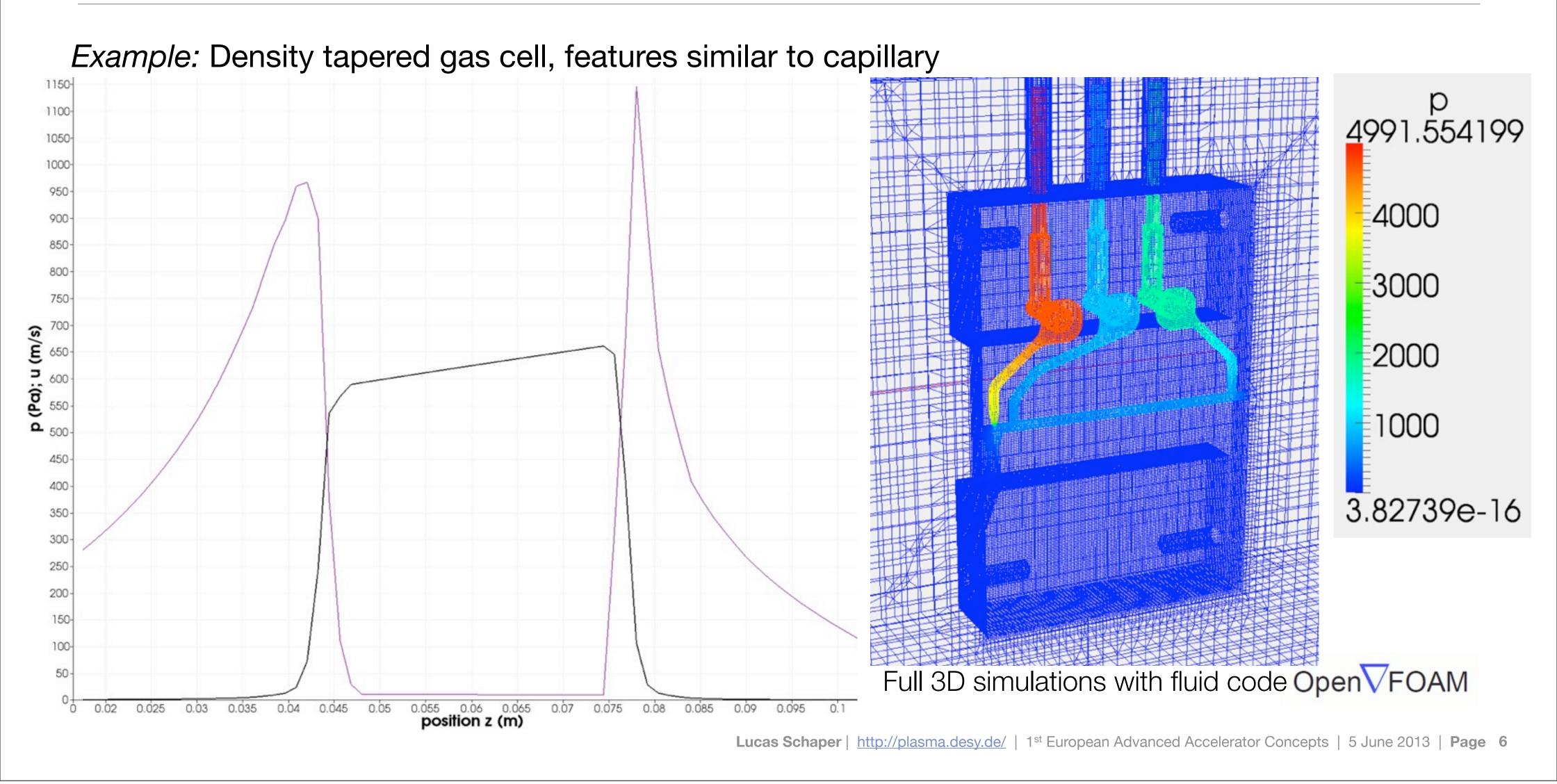


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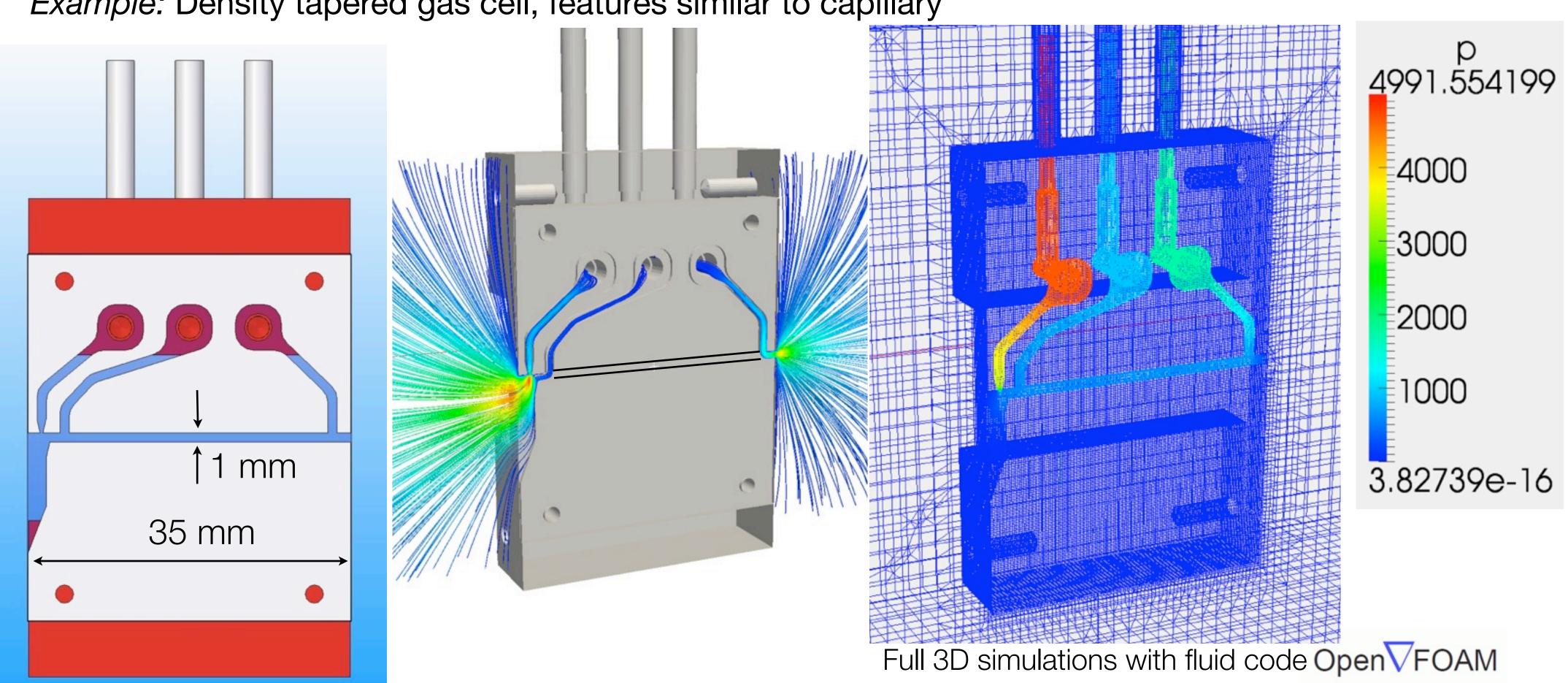


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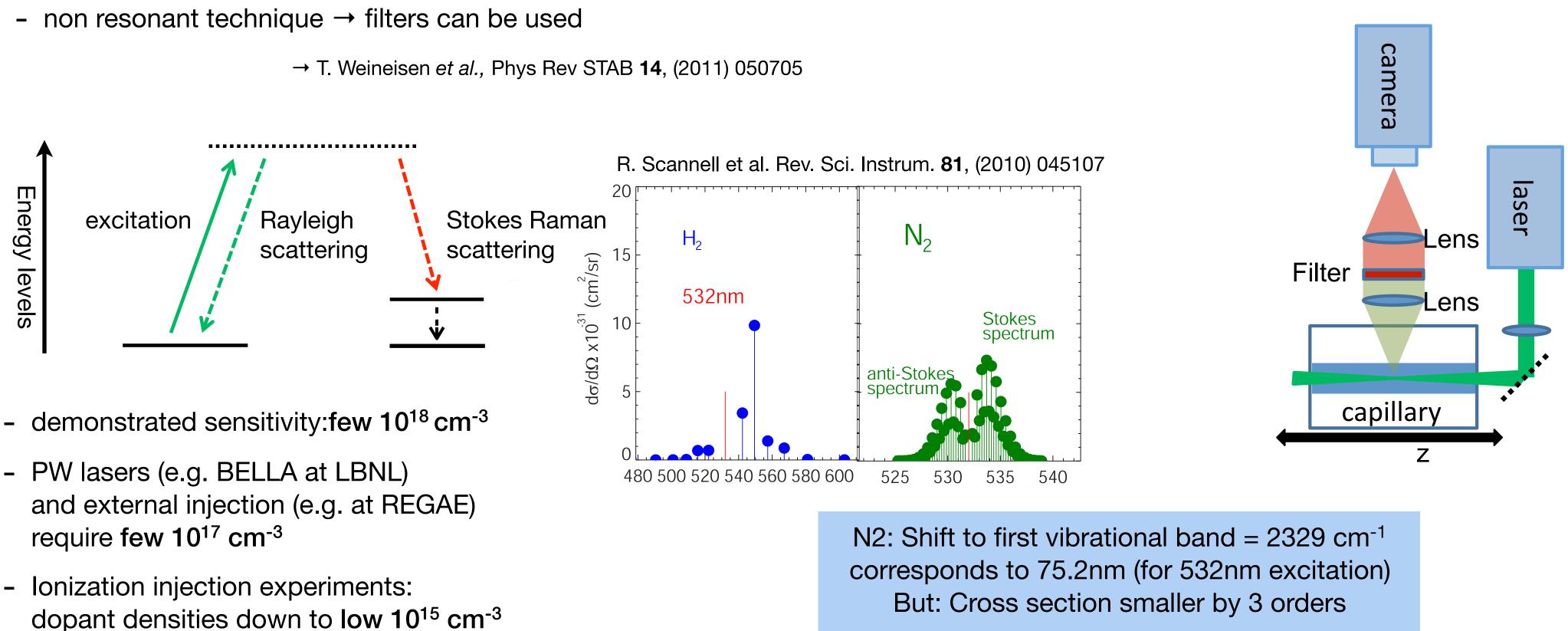
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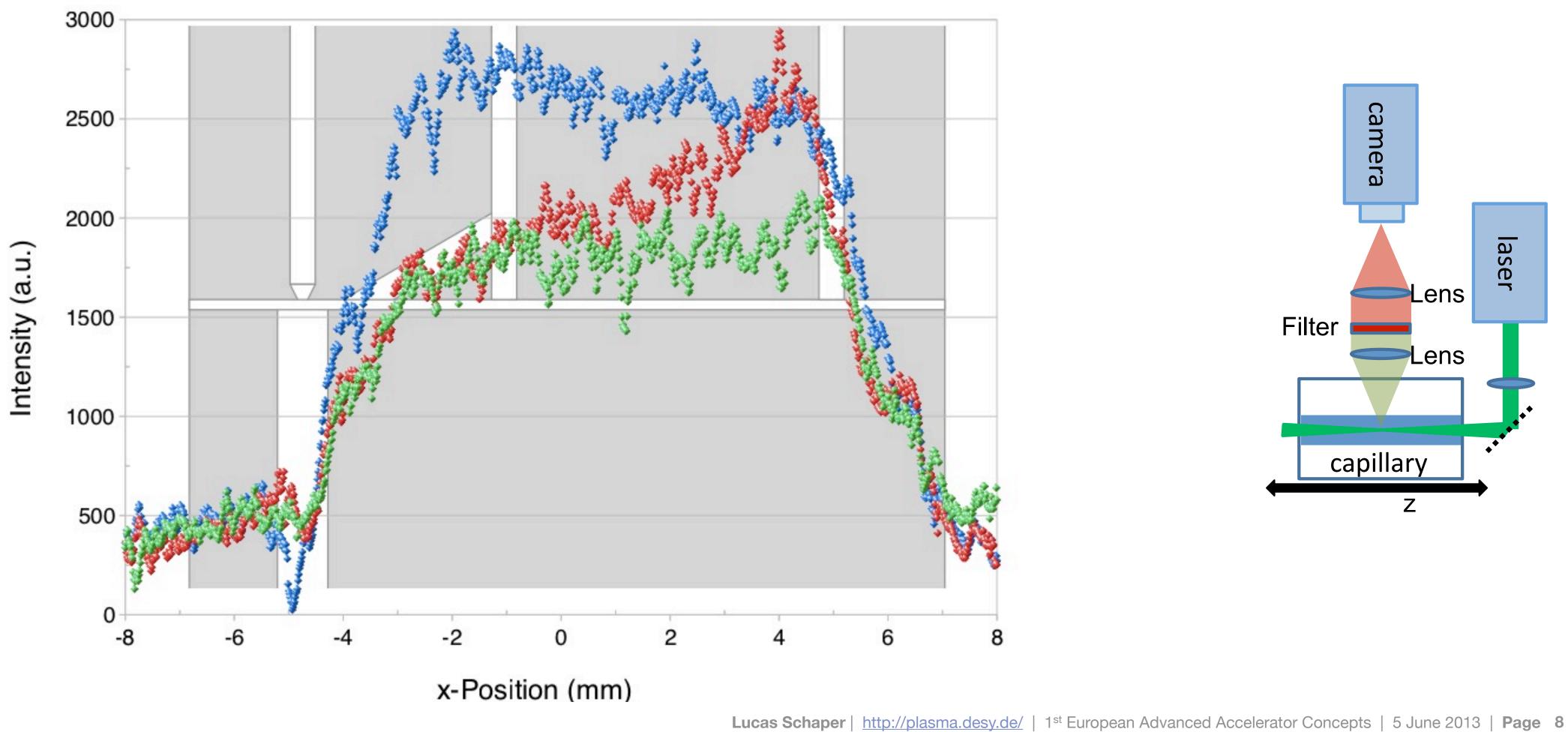
Raman scattering diagnostics: Setup

Technique: Raman scattering for longitudinal profile

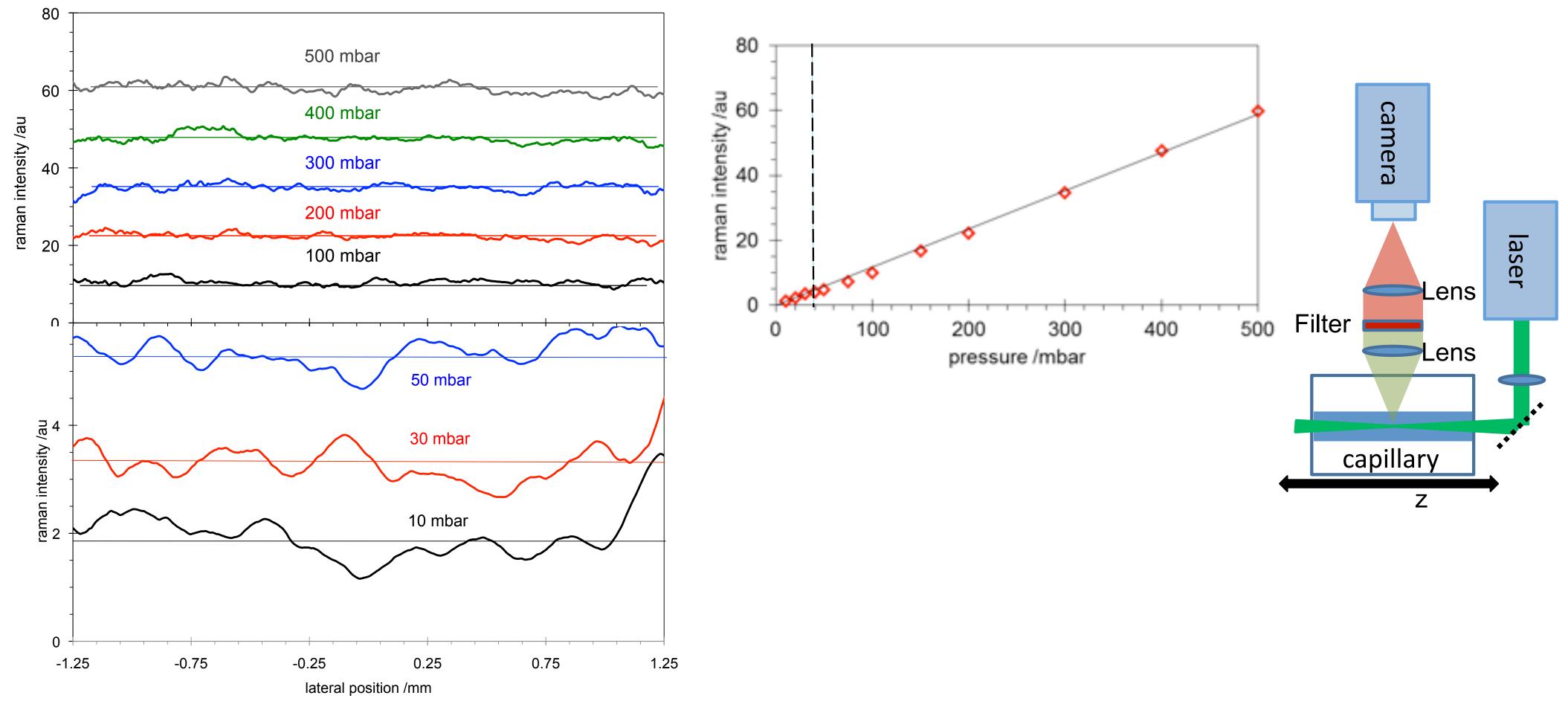
- scattered intensity proportional to gas density: $I_{Raman} = n_{Gas} \cdot \sigma \cdot I_{Laser}$
- -



Sensitive diagnostic important for profile characterization

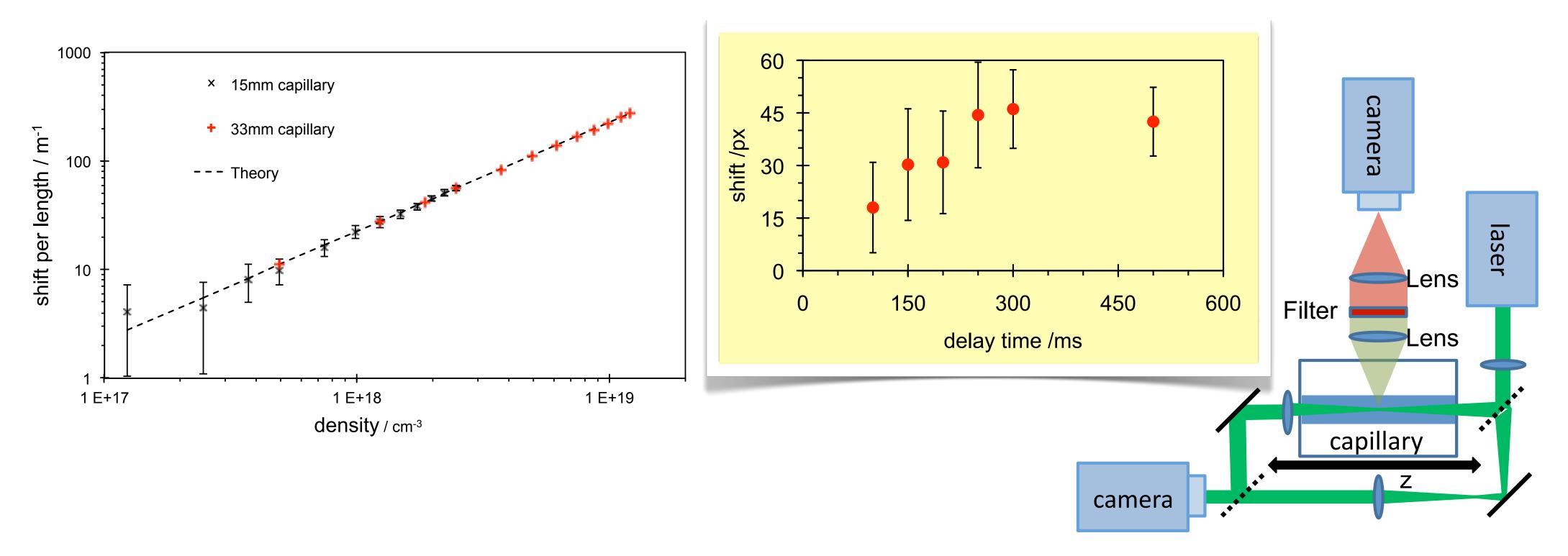


Sensitive diagnostic important for profile characterization



Sensitive diagnostic important for profile characterization

New technique: Raman scattering combined with longitudinal interferometry



- profile determination by Raman scattering in polished capillaries -
- integrated density under profile determined by interferometry

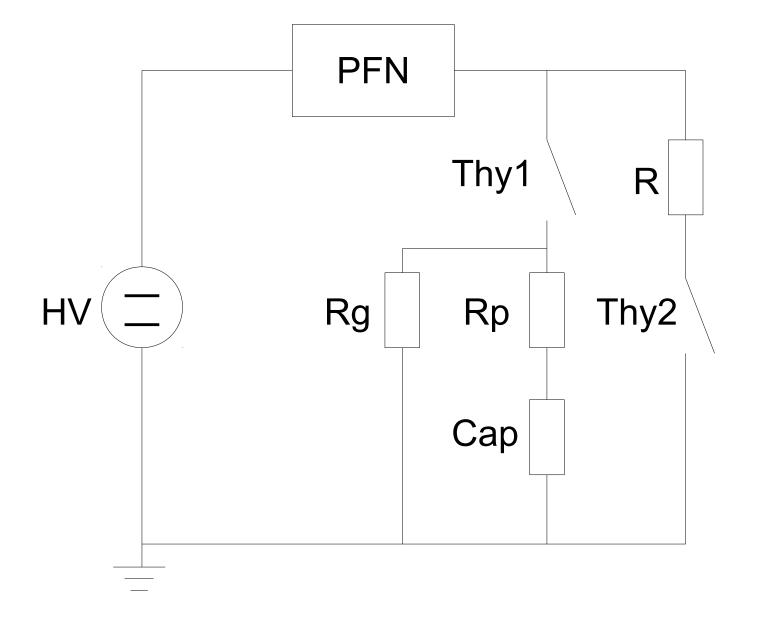
L. F. Schaper et al., in preparation

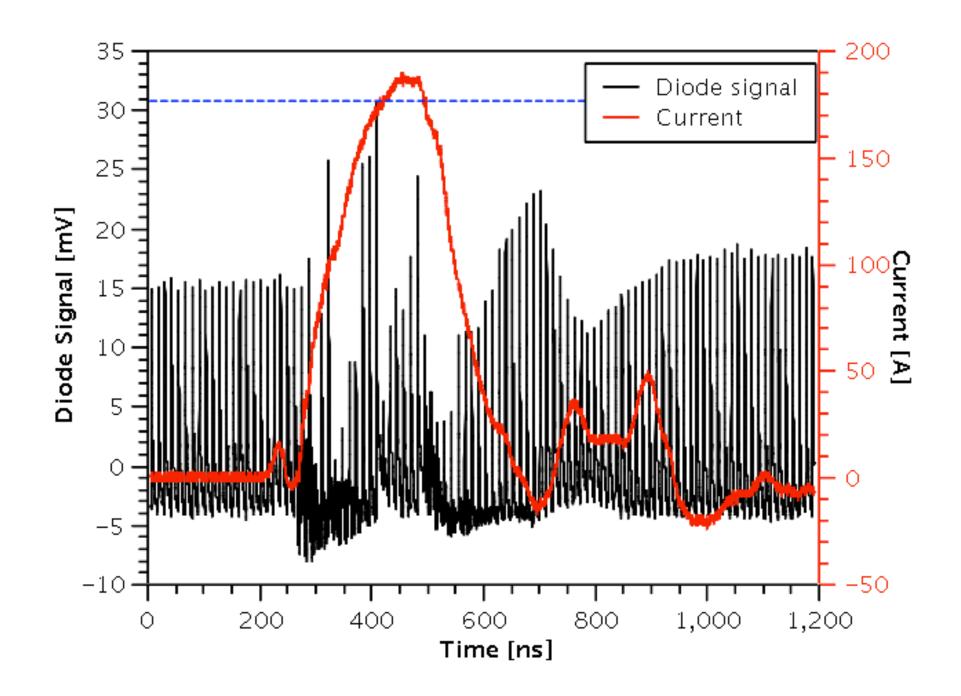
→ reconstruction of profile with high accuracy (currently being done)

Transverse density shaping

Technique: Laser guiding by transverse plasma channel, ignited through electric discharge

- PFN with adjustable pulse duration and either peak current or dl/dt
- Max voltage: 40kV max current: 1.5kA (tested so far) max pulse duration: 400ns
- shot to shot RMS jitter @ 15kV < 5ns

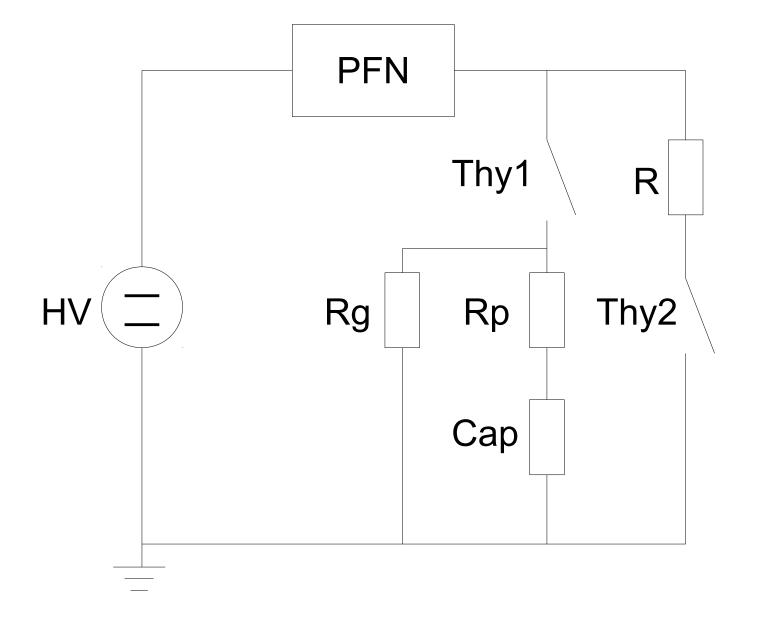




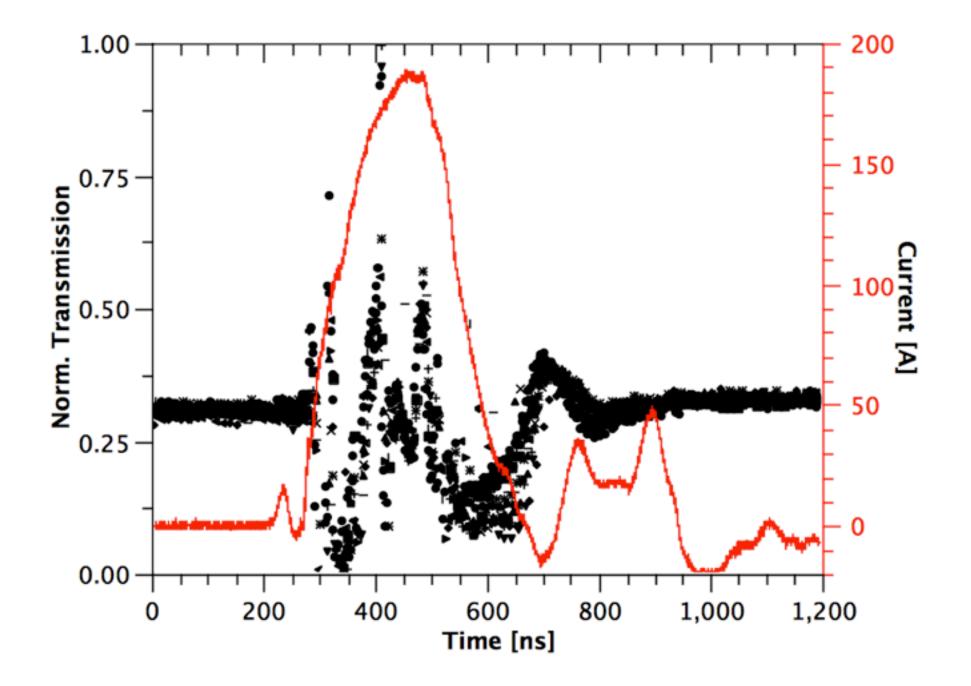
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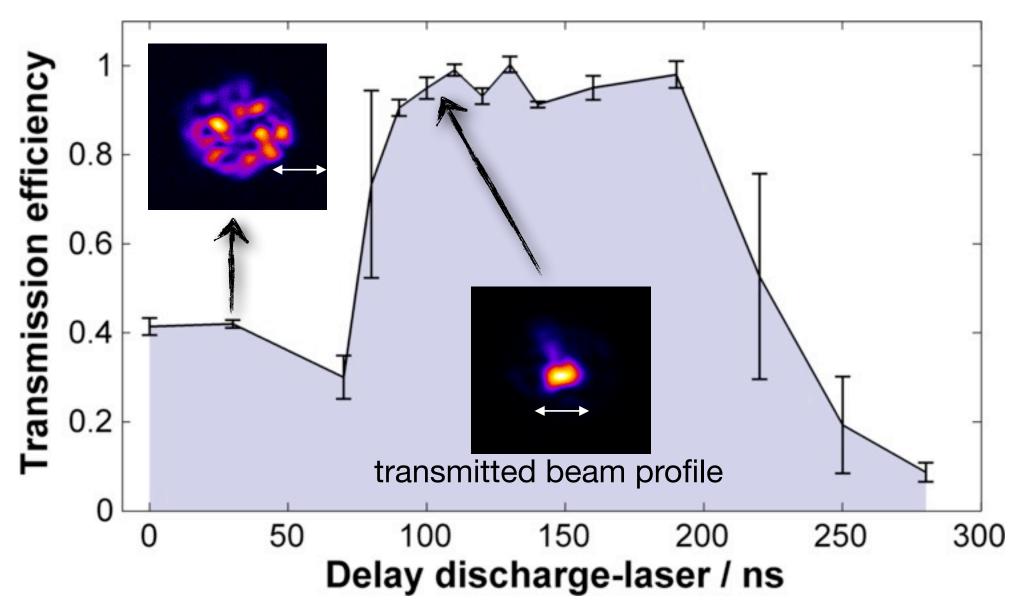
300 350 JUU

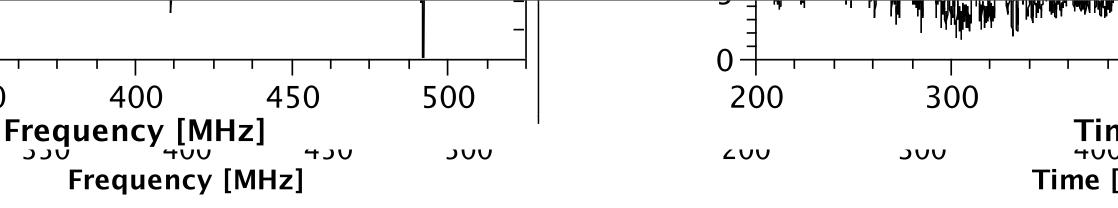
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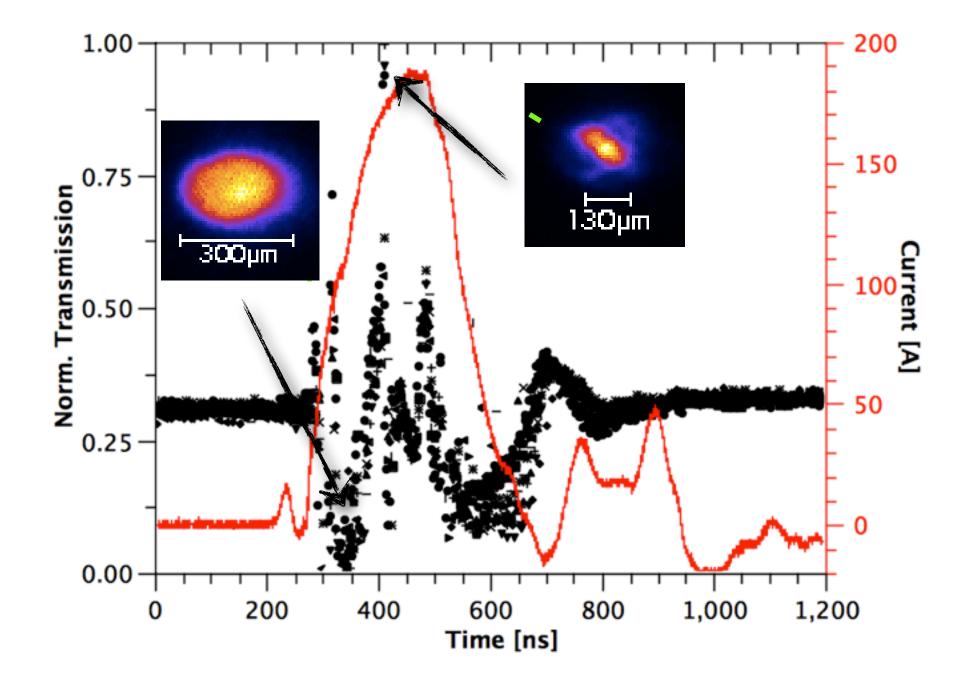
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guiding 15 mm long capillary, laser < 1 mm Rayleigh length





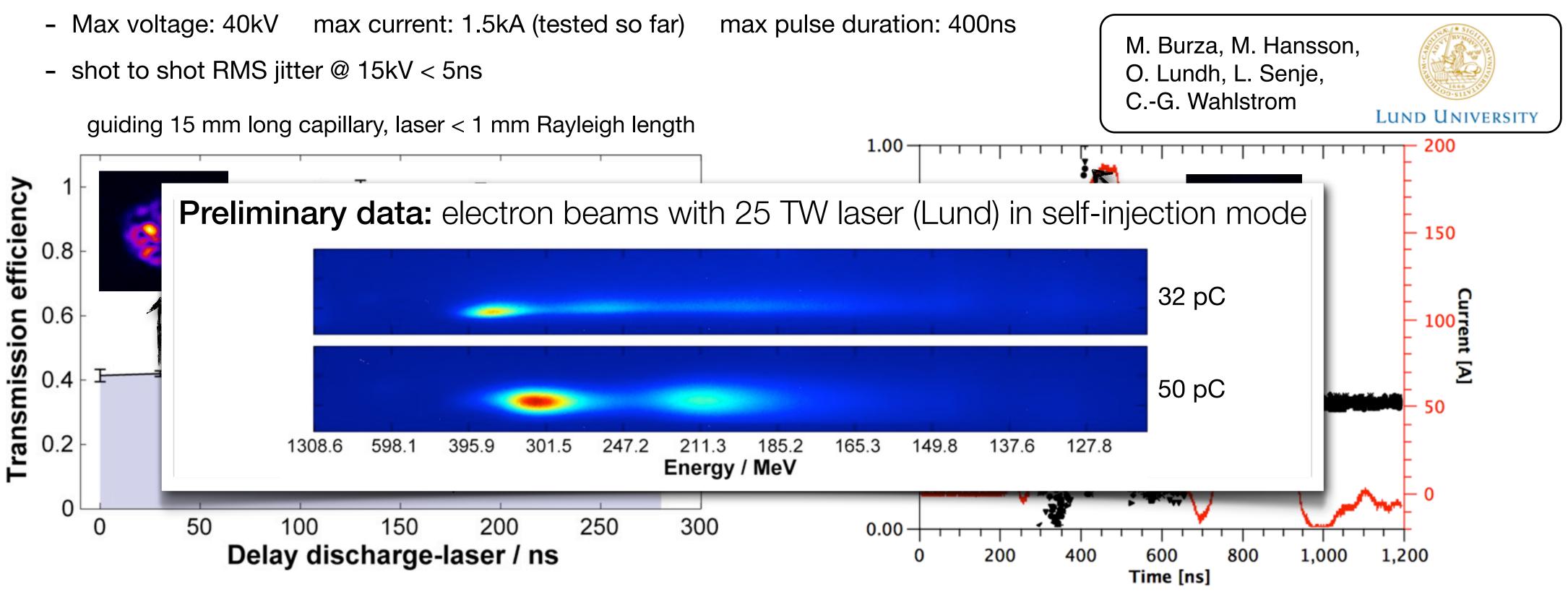


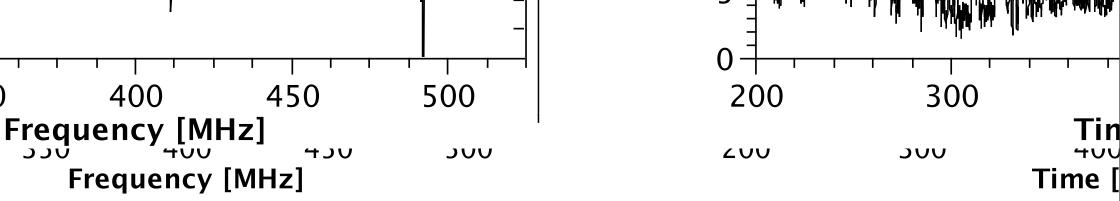
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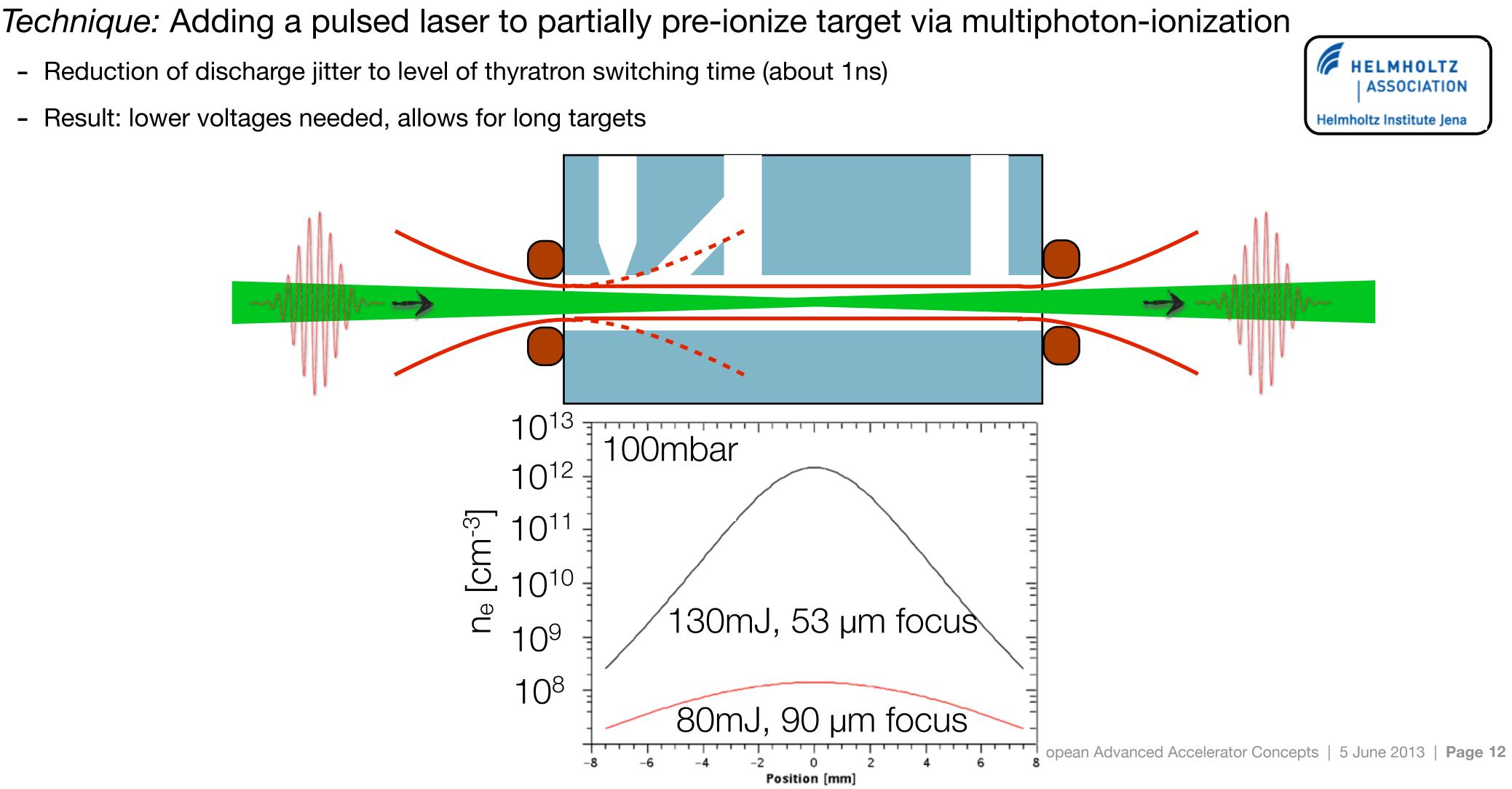
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Discharge seeding

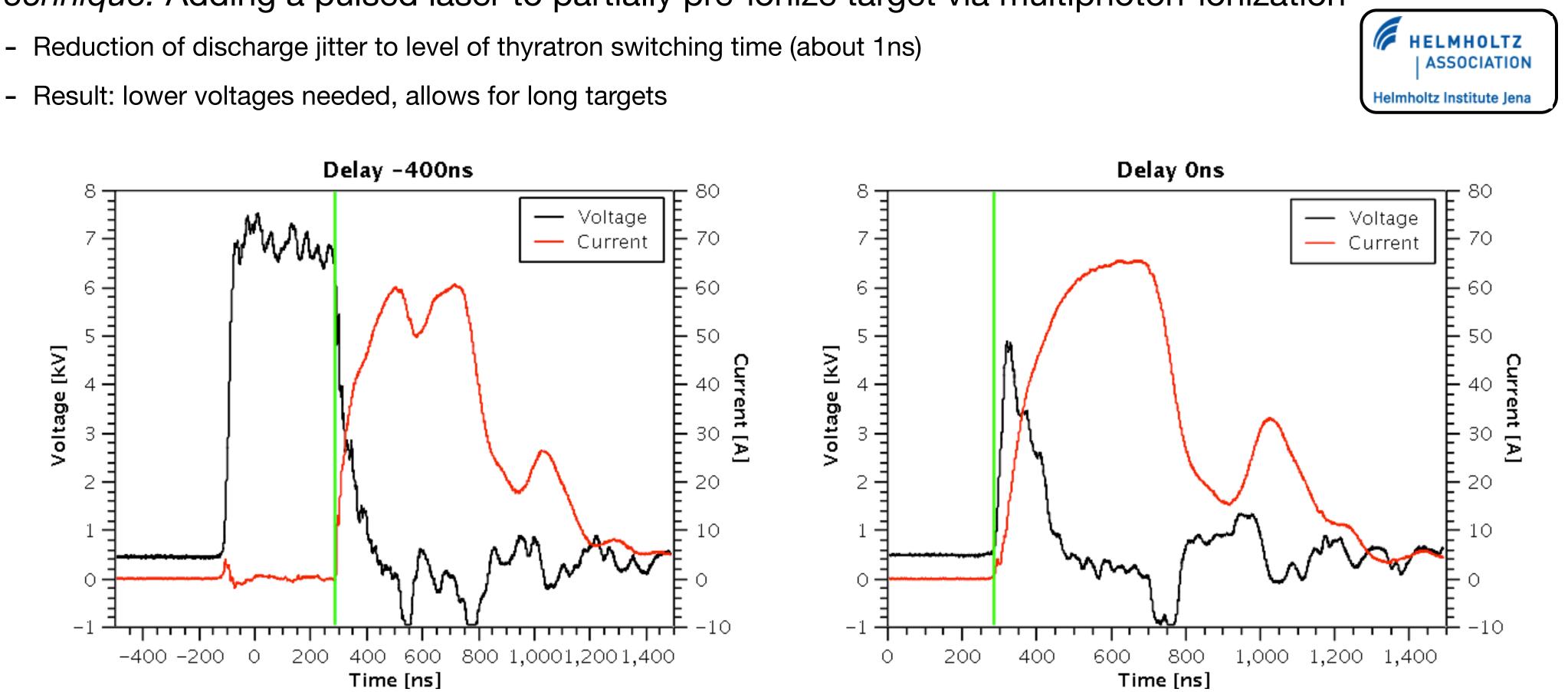
- Reduction of discharge jitter to level of thyratron switching time (about 1ns)
- Result: lower voltages needed, allows for long targets



Discharge seeding

Technique: Adding a pulsed laser to partially pre-ionize target via multiphoton-ionization

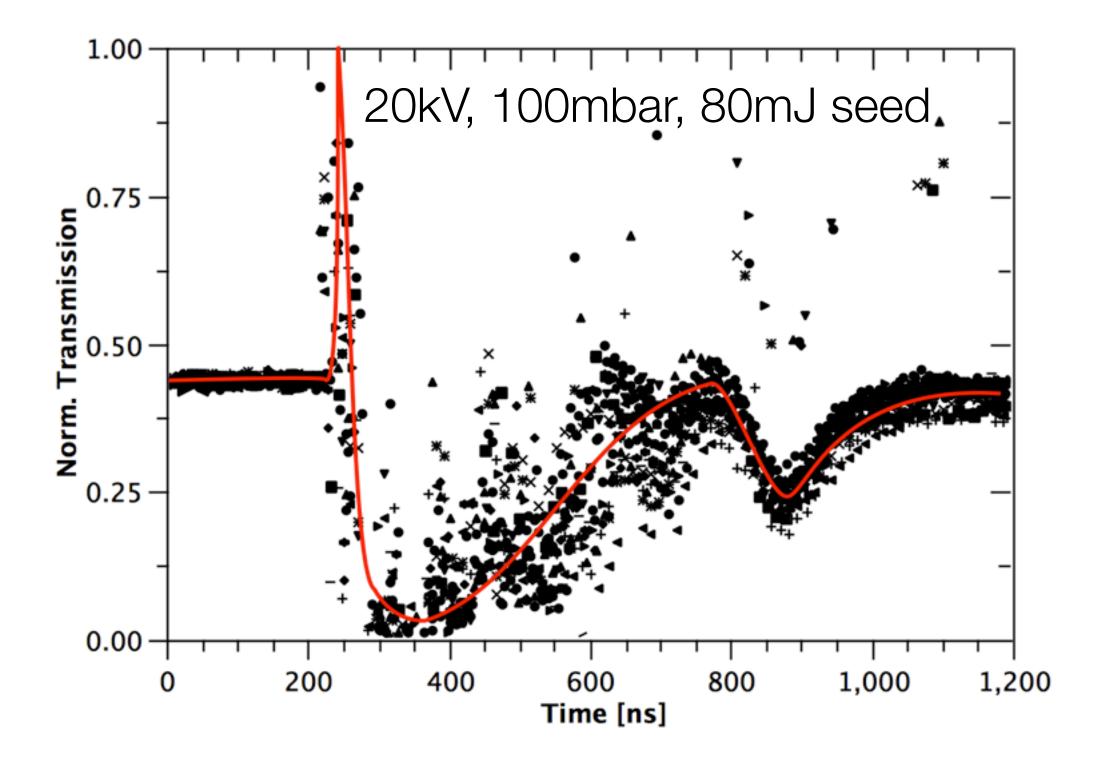
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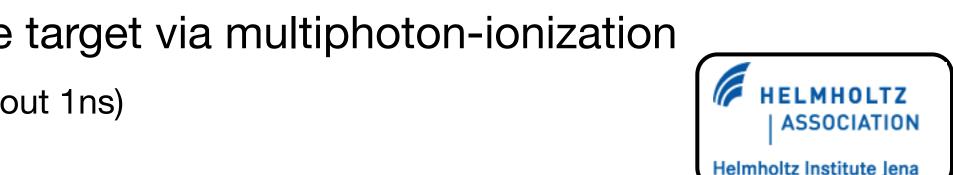


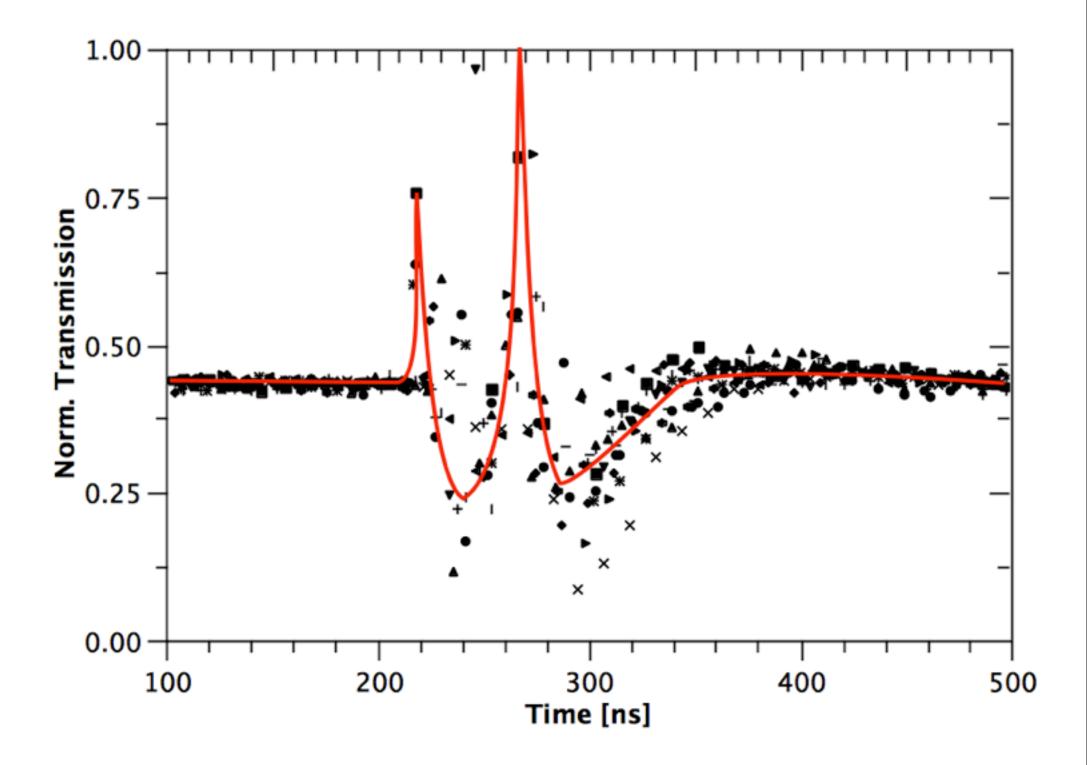
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Summary

Longitudinal density tailoring

- > Relative density profile measurement down to 10^{17} cm⁻³
- > Absolute density calibration for fringe shifts $< 5 \times 10^{-3}$ mm⁻¹
- results form simulations and measurements agree

Transverse density shaping

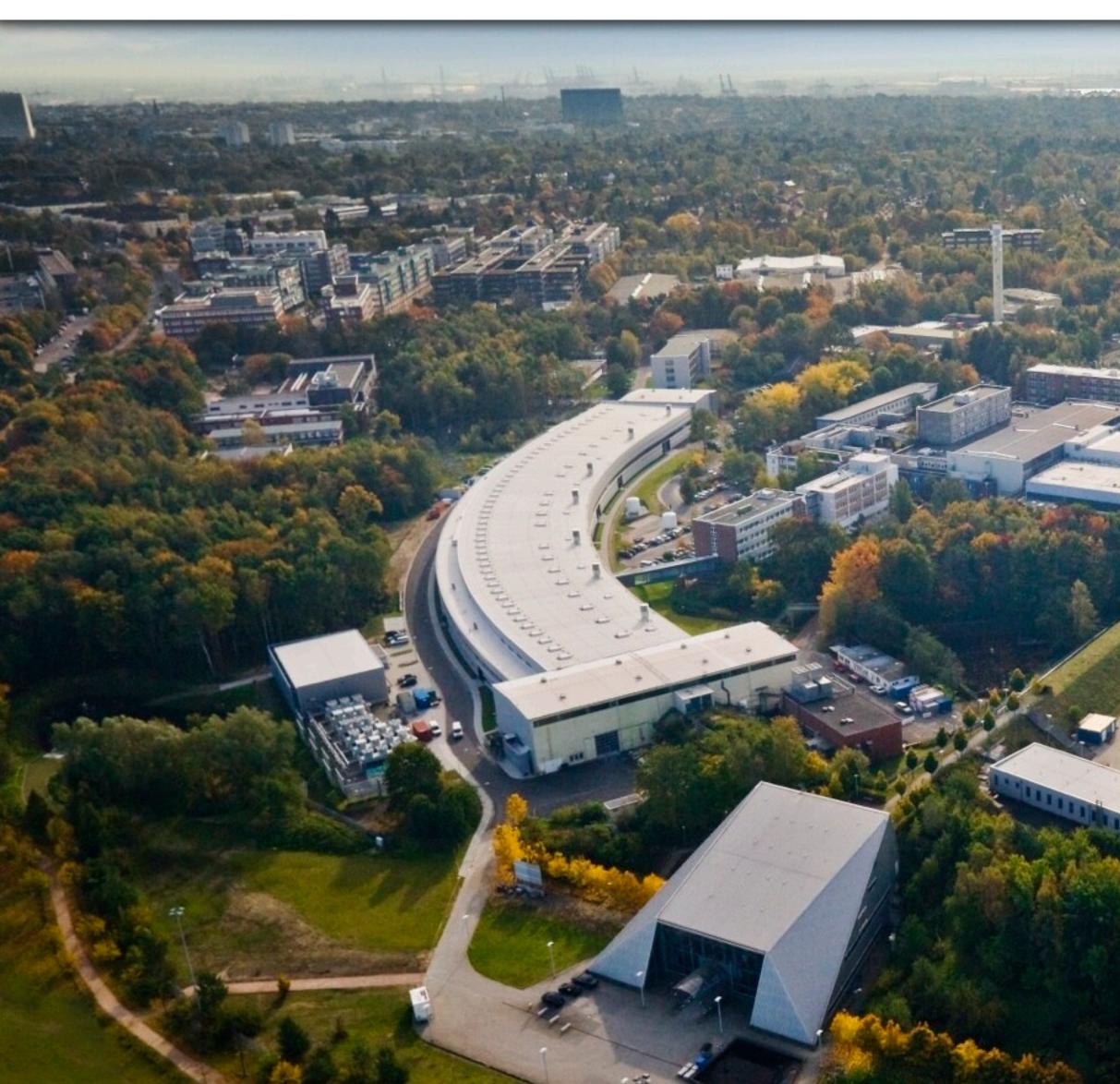
- > PFN allows flexible discharge parameters
- Iow discharge-on jitter in typical capillary length at typical voltages of about 20kV
- High transmission through capillaries with length >> Rayleigh length of the laser

> Discharge seeding

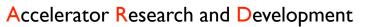
- increased stability and decrease discharge time lag
- > stable operation at lower voltages, longer capillaries possible
- > BUT: Not guiding (so far)













Virtual Institute for PWA at FLASH

Thank you for your attention!